

intervening claims, the Examiner has not rejected claim 7 except under 35 U.S.C. §112, second paragraph. Therefore, Applicants believe that claim 7 would be allowable if rewritten to overcome the rejection under 35 U.S.C. §112, second paragraph, and to include all of the limitations of the base claim and any intervening claims. Applicants respectfully submit that claims 7, 15, 16, 17, 23, 24, and 26 have been rewritten in independent form, some with minor edits, as new independent claims 29-35. Applicants respectfully submit that newly added claims 29-35 are allowable.

With respect to the rejection of claims 2, 3, 7, 8, 12, 13 and 17 under 35 U.S.C. §112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which the Applicants regard as the invention, Applicants have amended claims 2, 3, 7, and 8. Specifically, claim 2 has been amended to define that the "tank" contains the neutralizing compound, thereby distinguishing it from the nitrogen gas storage tank. In addition, claim 3 was amended to define that the heat exchange means is connected to the nitrogen gas storage tank via a second pipe. Claim 7 now depends from claim 3. And claim 8 was amended to delete reference to "a second section" and that the nitrogen vaporizer is attached to the second pipe for vaporizing the nitrogen from the nitrogen storage tank.

Applicants respectfully note that claim 12 depends from claim 2, which defines "a vacuum pump", so the rejection of claim 12 because "the vacuum pump" of claim 12 lacks antecedent basis is without merit. In addition, the Applicants respectfully point out that although the Examiner has rejected claim 13 under 35 U.S.C. §112, second paragraph, he has given no reasons as to why he has rejected the claim. Applicants respectfully request the Examiner to withdraw the rejections to claims 12 and 13.

With respect to the rejection of claims 1 and 18 under 35 U.S.C. §102(b) as being anticipated by Mehta et al., and with respect to the rejection of claim 1 under 35 U.S.C. §102(b) as being anticipated by Kubota et al., these rejections are respectfully traversed in view of the claims as amended and for the reasons that follow.

More specifically, independent claims 1 and 18 now define systems for cleaning pressurized containers containing chemicals therein wherein the containers are explicitly defined as being "pressurized". In addition, claims 1 and 18 have been amended to define that the nitrogen gas storage tank (claim 1) or the intake means (claim 18) are for feeding either nitrogen gas or air into the pressurized container to intermix with the quantity of chemicals contained within the pressurized container to form a nitrogen gas or air and

chemical mixture. In addition, claims 1 and 18 have been amended to define that the tank comprising the neutralizing material is utilized for receiving the nitrogen gas or air and chemical mixture. These elements are nowhere taught or even suggested by either Mehta et al. or Kubota et al.

Mehta merely relates to a process for drying semiconductor wafers or similar substrates. The wafers or other substrates are positioned in a chamber and filled with a processing fluid until the fluid overflows through a vacuum valve. Vacuum aspiration is continued to de-gas the chamber. A vacuum assist drain is opened and inert air is introduced above the draining fluid to dry the substrates. The chamber is then repressurized prior to opening the chamber to remove the dry substrates. Alternatively, a cleaning solution is introduced into the chamber to clean the wafers. In addition, Kubota et al. merely relates to a cleaning method for vacuum degreasing a work by cleaning it with a solvent vapor under reduced pressure and vacuum-cleaning the machine.

The present invention, however, relates to a system that is utilized to clean a pressurized container having a quantity of a chemical contained therein. Nitrogen gas or air is introduced into the pressurized container to mix with the quantity of the chemical therein. A tank having a neutralizing chemical contained therein is utilized to receive the nitrogen gas or air and chemical mixture for neutralizing the chemical.

Since neither Mehta et al. nor Kubota et al. disclose or teach the elements defined in amended claims 1 and 18, the rejections thereto under 35 U.S.C. §102(b) have been overcome and should be withdrawn.

Claims 2-17 depend from independent claim 1 and claims 19-28 depend from independent claim 18. These claims are further believed allowable over the references of record for the same reasons as set forth with respect to their parent claims since each sets forth additional structural elements of Applicants' novel systems.

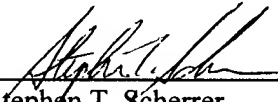
### CONCLUSION

In view of the foregoing remarks and amendments, Applicants respectfully submit that all of the claims in the application are in allowable form and that the application is now in condition for allowance. If, however, any outstanding issues remain, Applicants urge the Examiner to telephone the Applicants' attorney so that the same may

be resolved and the application expedited to issue. Applicants respectfully request the Examiner to indicate all claims as allowable and to pass the application to issue.

Respectfully submitted,

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